

two lock chambers for carrying in and carrying out said substrates to be subjected to processing or said substrates which have been subjected to processing;

a single atmospheric transferring device for transferring, one by one, a substrate to be subjected to processing or a substrate which has been subjected to processing, between said cassette in the air and said two lock chambers; and

opening and closing devices provided respectively at a side of the air of said two lock chambers and being opened or closed every carrying-in and carrying-out of said substrate to be subjected to processing or said substrate which has been subjected to processing, so as to change over said two lock chambers to being in an atmosphere or in a vacuum, wherein the method comprises the step of:

carrying in said substrate to be subjected to processing, or carrying out said substrate which has been subjected to processing, one by one, between the two lock chambers in the atmosphere and the cassette in the air, the opening and closing devices being opened and closed every carrying-in and carrying-out of said substrate, one by one.

3. (Amended) A method of transferring a substrate, using apparatus comprising:

a cassette table for mounting in air a cassette which receives plural substrates to be subjected to processing or plural substrates which have been subjected to processing;

a load lock chamber for carrying in said substrates to

be subjected to processing;

an unload lock chamber for carrying out said substrates which have been subjected to processing;

a single atmospheric transferring device for transferring one by one a substrate to be subjected to processing or a substrate which has been subjected to processing, between said cassette in the air and said load lock chamber and said unload lock chamber; and

opening and closing devices provided respectively at a side of the air of said load lock chamber and said unload lock chamber and being opened or closed every carrying-in and carrying-out of said substrate to be subjected to processing or said substrate which has been subjected to processing, so as to change over said load lock chamber and said unload lock chamber to be in an atmosphere or in a vacuum,

wherein the method comprises the step of:

carrying in said substrate to be subjected to processing, or carrying out said substrate which has been subjected to processing, one by one, between said load lock chamber and said unload lock chamber in the atmosphere and said cassette in the air, the opening and closing devices being opened and closed every carrying-in and carrying-out of said substrate, one by one.

Claim 8, line 20, after "processing," insert --one by one,--.

Claim 9, line 14, delete "or" and insert --and--;